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ATTORNEY DOCKET NO. CONFIRMATION NO. FIRST NAMED INVENTOR APPLICATION NO. FILING DATE BERNARD ASPAR 025219-268 5219 09/600,590 07/19/2000 EXAMINER 7590 04/19/2005 ROBERT E. KREBS KRUER, KEVIN R THELEN REID & PRIEST LLP ART UNIT PAPER NUMBER P.O. BOX 640640 SAN JOSE, CA 95164-0640 1773

DATE MAILED: 04/19/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)
Office Action Summary	09/600,590	ASPAR ET AL.
	Examiner	Art Unit
	Kevin R Kruer	1773
The MAILING DATE of this communication		
eriod for Reply		
A SHORTENED STATUTORY PERIOD FOR RE THE MAILING DATE OF THIS COMMUNICATIO  - Extensions of time may be available under the provisions of 37 CFF after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a  - If NO period for reply is specified above, the maximum statutory per  - Failure to reply within the set or extended period for reply will, by st Any reply received by the Office later than three months after the m earned patent term adjustment. See 37 CFR 1.704(b).	NN. R 1.136(a). In no event, however, may a reply within the statutory minimum of thi riod will apply and will expire SIX (6) MOI atule, cause the application to become A	reply be timely filed  rty (30) days will be considered timely.  NTHS from the mailing date of this communication.  BANDONED (35 U.S.C. § 133).
Status		
1) Responsive to communication(s) filed on 1!	<u>9 January 2005</u> .	
_	Γhis action is non-final.	
3) Since this application is in condition for allo	wance except for formal mat	ters, prosecution as to the merits is
closed in accordance with the practice under	er <i>Ex par</i> te Quayle, 1935 C.I	O. 11, 453 O.G. 213.
Disposition of Claims		
4)⊠ Claim(s) <u>1-17,19-29,31-35 and 49-51</u> is/are	e pending in the application.	
4a) Of the above claim(s) <u>2-12 and 25-28</u> is	· · · · · · · · · · · · · · · · · · ·	ration.
5) Claim(s) is/are allowed.		
6) Claim(s) <u>1,13-17,19-24,29,31-35, and 49-5</u>	11 is/are rejected.	•
7) Claim(s) is/are objected to.		
8) Claim(s) are subject to restriction an	id/or election requirement.	
Application Papers		
9)☐ The specification is objected to by the Exam	niner.	
10)⊠ The drawing(s) filed on 19 July 2000 is/are:	a)⊠ accepted or b)⊡ object	cted to by the Examiner.
Applicant may not request that any objection to	- · ·	• •
Replacement drawing sheet(s) including the cor		•
11) The oath or declaration is objected to by the	Examiner. Note the attache	d Office Action or form PTO-152.
riority under 35 U.S.C. § 119		
12)⊠ Acknowledgment is made of a claim for fore a)⊠ All b)□ Some * c)□ None of:	eign priority under 35 U.S.C.	§ 119(a)-(d) or (f).
1. Certified copies of the priority docum		
2. Certified copies of the priority docum		
3.⊠ Copies of the certified copies of the papplication from the International Bur		received in this National Stage
* See the attached detailed Office action for a		received
detailed detailed office action for a	not of the certified copies flot	. I COCIVEU.
ttachment(s)		
) Notice of References Cited (PTO-892)  Notice of Draftsperson's Patent Drawing Review (PTO-948)		Summary (PTO-413) sVMail Date
<ul> <li>Notice of Dransperson's Patent Drawing Review (P10-948)</li> <li>Information Disclosure Statement(s) (PTO-1449 or PTO/SB/Paper No(s)/Mail Date</li> </ul>	/08) 5) 🔲 Notice of I	s)/Mail Date nformal Patent Application (PTO-152)
	6) Other:	

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#### **DETAILED ACTION**

#### Election/Restriction

1. Claims 2-12 and 25-28 are withdrawn from further consideration pursuant to 37 CFR 1.142(b) as being drawn to a nonelected method of making a compliant substrate, there being no allowable generic or linking claim. Election was made **without** traverse in Paper No. 8.

### Claim Rejections - 35 USC § 112

- 2. The following is a quotation of the first paragraph of 35 U.S.C. 112:
  - The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.
- 3. Claims 1, 19-24, 31-34 and 50 are rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the written description requirement. The claim(s) contains subject matter which was not described in the specification in such a way as to reasonably convey to one skilled in the relevant art that the inventor(s), at the time the application was filed, had possession of the claimed invention. The original disclosure does not contain support for a compliant substrate "having a buried layer of microcavities delimiting a superficial thin layer of microcavities."

## Double Patenting

4. Claim 31 is objected to under 37 CFR 1.75 as being a substantial duplicate of claim 19. When two claims in an application are duplicates or else are so close in content that they both cover the same thing, despite a slight

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difference in wording, it is proper after allowing one claim to object to the other as being a substantial duplicate of the allowed claim. See MPEP § 706.03(k).

### Claim Rejections - 35 USC § 102

- 5. The text of those sections of Title 35, U.S. Code not included in this action can be found in a prior Office action.
- 6. Claims 1, 13-17, 19-23, 29, 31-33, 35, 50, and 51 are rejected under 35 U.S.C. 102(b) as being anticipated by Bisaro et al (US 5,141,894).

Bisaro teaches a compliant substrate as depicted in Figure 4d. The laminate comprises a substrate (10), a monocrystalline zone (13) made by implanting ions through the substrate (col 4, lines 64+), a preliminary layer (11) on said monocrystalline zone (col 4, line 52+), an epitaxial growth layer (16) on said preliminary layer (col 5, lines 12+) which can be ion implanted (15), and a final layer of epitaxial growth layer (17). Ion that can be implanted include Mn, Al, Si, Cr, Fe, Ni Co, Cu, Ge, Sn, Zn Cd, Ti C, Cl, B, Ar, P, Le, Au, Ni, oxygen, hydrogen, fluorine, Si, Br, and S (col 3, lines 37+). The layers may comprise crystalline, semiconductor materials such as silicon, germanium, or the like (col 6, lines 34+).

With regard to claim 1 and the claims that depend therefrom, the substrate layer is understood to read on the claimed "carrier layer;" The microcrystalline zone is understood to read on the claimed "buried layer of microcavities;" and the epitaxial layer (16) is understood to read on the claimed "thin layer." The ion implantation (15) of the epitaxial layer (16) is understood to read o the claimed "pre-stressed layer" of claim 19 and the claimed "implantation" step of claim 21.

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the ion is understood to read on the claimed "foreign element" of claims 21 and 32 and the claimed "doping agent" of claim 22.

With regard to claim 35 and the claims that depend therefrom, the ion implantation of the substrate reads on the claimed "joining means" of claim 35. The ion implantation of the substrate is taught to create anchoring points that are centered at a depth Rp and having a width of 2.35XR0 (col 3. lines 46+). The epitaxial growth layer reads on the claimed "thin layer" of claim 35. The claimed "intermediate layer" of claim 15 is met by the preliminary layer (11). Bisaro teaches the intermediate layer may be made from GaAs (see Fig 4d), arsenic, gallium, Si, or a number of other materials (col 4, lines 57+). Since the layer is amorphous, the examiner takes the position it is inherently "non-homogeneous."

With respect to claim 13, the bonding energy between the epitaxial growth layer (16) (which reads on the claimed "the thin layer") and the epitaxial growth layer (17) is altered by ion implantation. Ion implantation is known to affect the surface's roughness that would read on the claimed "defects."

# Claim Rejections - 35 USC § 103

7. Claims 24, 34, 44, and 49 are rejected under 35 U.S.C. 103(a) as being unpatentable over Bisaro et al. (US 5,141,894), as applied to claims 1, 13-17, 19-23, 29, 31-33, 35, 50, and 51 above, and further in view of Yamashita (US 3,742,318).

Bisaro is relied upon as above. Specifically, Bisaro teaches that the epitaxial growth layer (17) may comprise semiconductor layers such as silicon. Bisaro does not teach that silicon alloys may be utilized. However, Si, Ge, and

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SiC are known in the art as semiconductors that can be used interchangeably (see '318, col 3, lines 16+). In order to rely on equivalence as a rationale supporting an obviousness rejection, the equivalency must be recognized in the prior art, In re Ruff, 256 F.2d 590, 118 USPQ 340 (CCPA 1958). Thus, it would have been obvious to utilize SiC as the semiconductor of the epitaxial growth layers taught in Bisaro because Yamashita teaches that it is used interchangeably in the semiconductor art with Si and Ge.

### Response to Arguments

Applicant's arguments filed January 19, 2005 have been fully considered but they are not persuasive.

Applicant argues that Bisaro does not teach a buried layer of microcavities inside a substrate. Instead, Bisaro teaches a compliant substrate as depicted in Figure 4d. The laminate comprises a substrate (10), a monocrystalline zone (13) made by implanting ions through the substrate (col 4, lines 64+), a preliminary layer (11) on said monocrystalline zone (col 4, line 52+), an epitaxial growth layer (16) on said preliminary layer (col 5, lines 12+) which can be ion implanted (15), and a final layer of epitaxial growth layer (17). Applicant's arguments are not persuasive. With regard to claim 1, the substrate, preliminary layer, and epitaxial growth layer are understood to read on the claimed "substrate." The ion implantation of the epitaxial growth layer (16) is read to read on the claimed micro-cavities, and epitaxial group layer (17) reads on the claimed thin layer.

Applicant further argues that Bisaro does not teach or suggest means to absorb due to hetero-epitaxial growth. Applicant further argues, with regard to

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the rejection of claims 24, 34, 44, and 49 as being unpatentable over Bisaro in view of Yamashita, neither reference teaches or suggests that "stresses brought to said compliant substrate are absorbed in whole or in part by the thin layer and/or micro-cavities." The examiner respectfully disagrees. Bisaro teaches that the invention "enables a considerable reduction in the number of dislocations spreading in the layer being formed (col 1, lines 65+)." Furthermore, Bisaro teaches "by ion implantation, there are created either anchoring points for the dislocation preventing their spread towards the surface or zones of stresses.... making the fine wafer less stressed and less curved (col 2, lines 14+)."

Thus, Applicant's arguments are not persuasive.

#### Conclusion

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will

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the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Kevin R Kruer whose telephone number is 571-272-1510. The examiner can normally be reached on Monday-Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carol Chaney can be reached on 571-272-1284. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Kevin R. Kruer

K-RX

Patent Examiner-Art Unit 1773